Icemos Technology Ltd Product Specification 1003.661501 Issue Date 14 January 2020 09:49

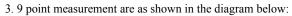
Part Number	Customer	

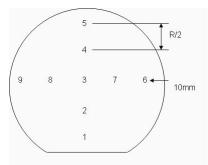
Category		Parameter	Specification	Measurement Method
OverallWafer	1.0	Diameter	100.00 +/- 0.50 mm	
	2.0	Primary Flat Orientation	{110}+/- 0.5 degree	Wafer Vendor
	3.0	Primary Flat Length	32.50 +/- 2.50 mm	Wafer Vendor
	4.0	Secondary Flat Orientation	None or Semi Standard	
	5.0	Secondary Flat Length	18.00 +/- 2.00 mm	Wafer vendor
	6.0	Overall Thickness	500.00 +/- 12.00 μm	ADE, 100%
	7.0	Total Thickness Variation (TTV)	<5.00μm	Guaranteed by Process
	8.0	Bow	<20.00μm	ADE to ASTM F534, 20%
	9.0	Warp	<20.00μm	ADE to ASTM F657, 20%
	10.0	Edge Chips	0	Bright Light, 100% (note 2)
	11.0	Edge Exclusion	5mm	
	12.0	Edge Rounding	Round with STANDARD EDGE	IceMOS proprietary processing
HandleSilicon	13.0	Handle Growth Method	CZ	Wafer Vendor
	14.0	Handle Orientation	{100} +/- 0.5 degree	Wafer Vendor
	15.0	Handle Thickness	500.00 +/- 12.00 μm	ADE, 100%
	16.0	Handle Doping Type	P	Wafer Vendor
	17.0	Handle Dopant	Boron	Wafer Vendor
	18.0	Handle Resistivity	1 - 10 Ohmcm	Wafer Vendor
	19.0	Backside Finish	Polished with light handling marks. No lasermarking	Guaranteed by process
	20.0	Total LPD Count	<50.00pcs	@0.3um, Tencor 6220 particle counter
	21.0	Total scratch length	Front side <10mm total length	Bright Light, 100% (note 2)
	22.0	Surface Haze	none	Bright Light, 100% (note 2)

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Part Number		Customer		
Category	Parameter	Specification	Measurement Method	
Shipping Details	Wafer per box :	Max 25		
	Packaging:	Taped Polypropylene Wafer Box Empak, Ultrapak, 100.00mm Antistatic Double Bagging		
	Lot Shipment Data	Device Thickness Bow / Warp Data Handle and SOI Thickness		
Explanatory Notes	1. Microscope inspec	ction performed using microscope scan as below. 5x objective.		
	2. All bright light inspections performed exclude all wafer area outside the edge exclusion defined in Overall			

2. All bright light inspections performed exclude all water area outside the edge exclusion defined in Overal Wafer, Edge Exclusion. High intensity bright lamp inspection as per ASTM F523.





Additional Information